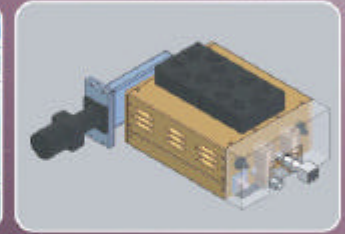
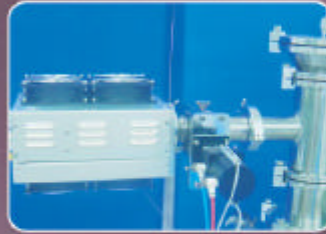
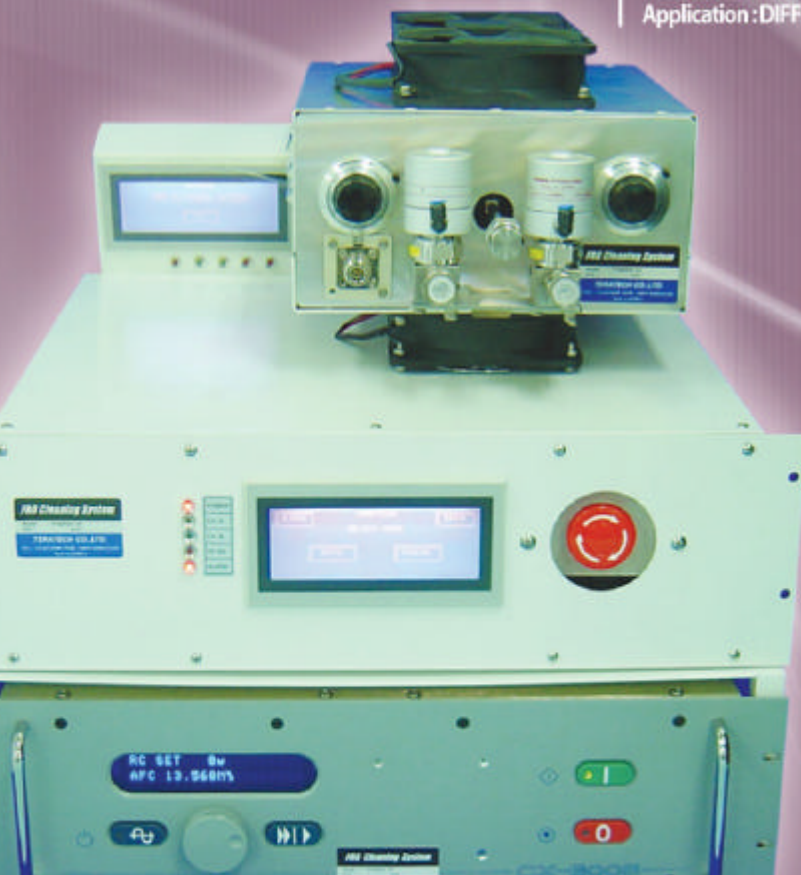


FRG Plasma Cleaning System



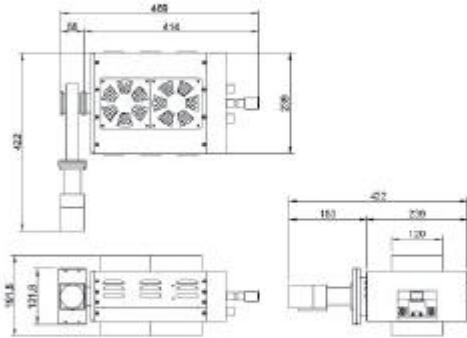
Plasma Cleaning for Vacuum Pump & Foreline
Cost Saving for Pump & Foreline maintenance
Reduction of the M/C downtime - Productivity Improvement
Cost Saving for Wafer damages from Particles
No impact on Process
Application : DIFF / CVD / METAL / ETCH



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TEL. +82-31-653-8360 F. +82-31-653-8361 (www.semitera.com)

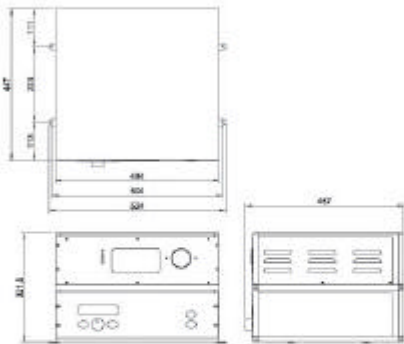
Plasma Reactor Unit



General Specification

Power	AC208~230V, 50/60Hz, 1 ϕ , 30A Power Consumption : Max. 20A
GAS	NF3 : 60 psig (400~1000 sccm) O2 : 50 psig (100~200 sccm)
Compressed Air for Valve (CDA or N2)	4~7 BAR (60~100 psig)

RF Generator & Controller Unit



System Component

TFG600A-2A 2-channel	TFG600A-1A 1-channel
<ul style="list-style-type: none"> • Plasma Reactor - 2 unit • RF-Generator - 1 unit • Controller - 1 unit • AGV40 - 2 EA 	<ul style="list-style-type: none"> • Plasma Reactor - 1 unit • RF-Generator - 1 unit • Controller - 1 unit • AGV40 - 1 EA

Accessory Parts (option)

V.M.P (Valve Manifold Panel)	Gas test kit
Foreline adapter	Gas inlet tube (1/4" flexible)